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•	SERIAL NUMBER 09/669,159	FILING DATE 09/25/2000 RULE _	Ó	CLASS 438	GRO	GROUP ART UNIT 1763		ATTORNEY DOCKET NO. TS2000-143		
	APPLICANTS Horng-Wen Chen, Taichung, TAIWAN;									
	Chi-How Wu, Tainan, TAIWAN;									
	** CONTINUING DATA **********************************									
المر	** CONTINUING DATA **********************************									
	IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 11/07/2000 -									
	Foreign Priority claimed 35 USC 119 (a-d) conditions met Verified and Acknowledged Priority claimed yes no Met after Allowance Examiners Signature Initials			TAIWAN	SHE		-		INDEPENDENT	
					DRAWING 6		CLAIMS 20		CLAIMS 3	
1	ADDRESS									
	George O Saile									
	20 McIntosh Drive Poughkeepsie ,NY 12603									
	TITLE									
	In-situ strip process for polysilicon etching in deep sub-micron technology									
							☐ All Fees			
	RECEIVED No.	ES: Authority has been given in Paper to charge/credit DEPOSIT ACCOUNT for following:			1.16 Fees (Filing)					
					UNT	1.17 Fees (Processing Ext. of time)				
					1.18 Fees (Issue)					
					Other					
							Credit			